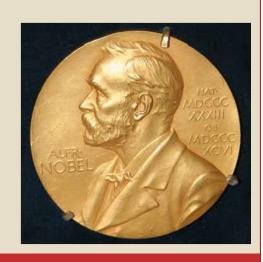
# Technology Trends as Viewed in 2011

Scaling the Conventional Transistors Future Nanoelectronic Devices

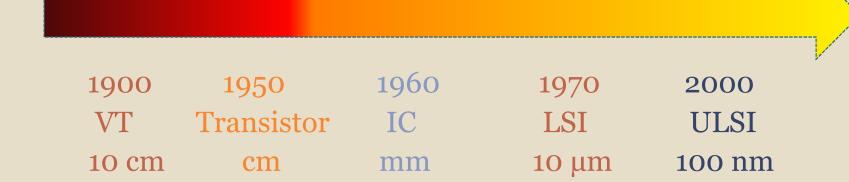
#### Nobel Prizes in Electron Devices

- 1956 The Transistor William Shockley, John Bardeen, and Walter Brattain
- 1973 Tunneling Diode
   Leo Esaki, Ivar Giaever
  - Josephson JunctionBrian David Josephson
- 2000 Integrated Circuit
   Jack Kilby
  - Semiconductor Heterojunction Devices
     Zohres Alferov and Herbert Kroemer
- 2007 Giant Magnetoresistive Effect (GMR)
   Albert Fert and Peter Grunberg
- 2009 Charge Coupled Devices
   George Smith and Willard Boyle
  - Fiber Optic TechnologyCharles Kao By



## Technology Trends: Scaling

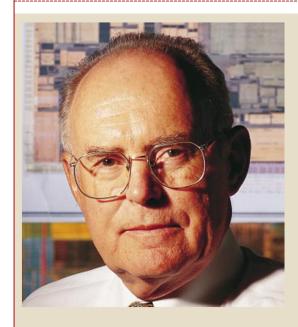
Downsizing of the components has been the driving force for circuit evolution:



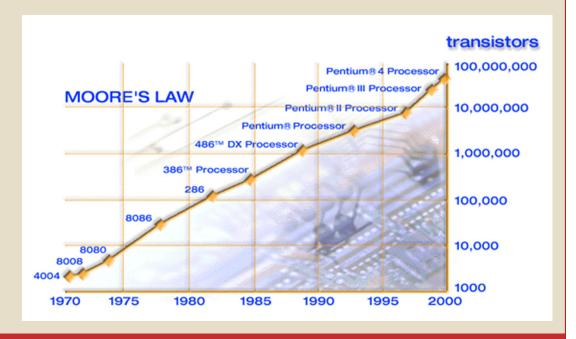
In 100 years, the size reduced by one million times.

We have never experienced such a tremendous reduction of devices in human history.

# Transistor Scaling: Moore's Law



Gordon Moore "every 1.5 years complexity doubles"



#### Technology Trends: Scaling



- Reduce Capacitance
  - ▼ Reduce switching time of MOSFET
  - Increase clock frequency
    - Increase Circuit operation Speed
- Increase number of transistors
  - Parallel processing
    - Increase Circuit operation Speed

Downsizing contributes to the performance increase in two ways.

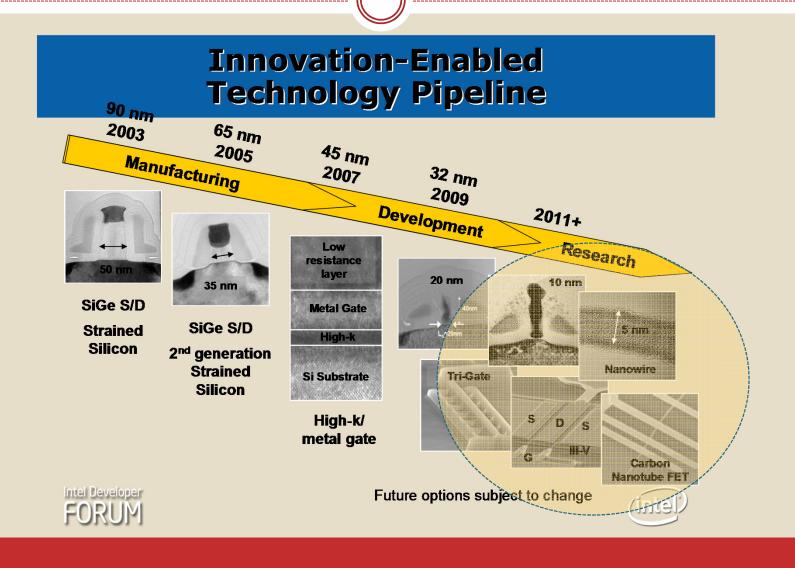
Thus, downsizing of Si devices is the most important and critical issue.

# Technology trends: Constant Field Scaling



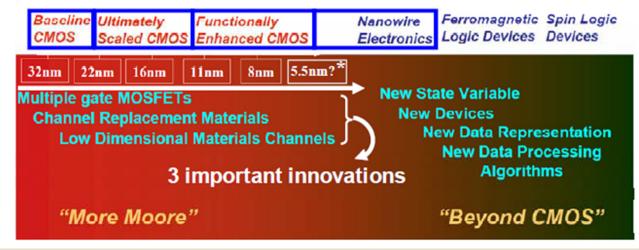
Geometry & Supply voltage	L <sub>g</sub> , W <sub>g</sub> T <sub>ox,</sub> V <sub>dd</sub>	К	Scaling K: K=0.7 for example		
Drive current in saturation	l <sub>d</sub>	K	$I_{d} = V_{sat}W_{g}C_{o}(V_{g}-V_{th})$ $C_{o}: gate C per unit area$ $W_{g}(t_{ox}^{-1})(V_{g}-V_{th}) = W_{g}t_{ox}^{-1}(V_{g}-V_{th}) = KK^{-1}K=K$		
I <sub>d</sub> per unit W <sub>g</sub>	I <sub>d</sub> /μm	1	$I_d$ per unit $W_g = I_d / W_g = 1$		
Gate capacitance	C <sub>g</sub>	K	$C_g = \varepsilon_o \varepsilon_{ox} L_g W_g / t_{ox}$ $\longrightarrow$ KK/K = K		
Switching speed	τ	K	$\tau = C_g V_{dd} / I_d \longrightarrow KK / K = K$		
Clock frequency	f	1/K	$f = 1/\tau = 1/K$		
Chip area	A <sub>chip</sub>	α	$\alpha$ : Scaling factor $\longrightarrow$ In the past, $\alpha > 1$ for most cases		
Integration (# of Tr)	N	α/K²	N $\rightarrow \alpha/K^2 = 1/K^2$ , when $\alpha=1$		
Power per chip	Р	α	fNCV <sup>2</sup> /2 $\longrightarrow$ K <sup>-1</sup> ( $\alpha$ K <sup>-2</sup> )K (K <sup>1</sup> ) <sup>2</sup> = $\alpha$ = 1, when $\alpha$ =1		

## Scaling of Today's Devices



#### Future Device Technologies: ... More Moore

- -Even After reaching the down-scaling limit, we could still continue R & D, seeking sufficiently higher Id-sat under low Vdd.
- -Three important technologies
  - 1. High-k/metal gate stack with <0.5nm EOT, Silcide S/D
  - 2. Si Nanowire MOSFETs
  - 3. Alternative channel MOSFETs (III-V, Ge), maybe nanowire
- Other Beyond CMOS devices are still in the cloud.



ITRS figure edited by Iwai

#### More than Moore ...

• 1969 Lambe and Jaklevic: Charge quantization in a small box

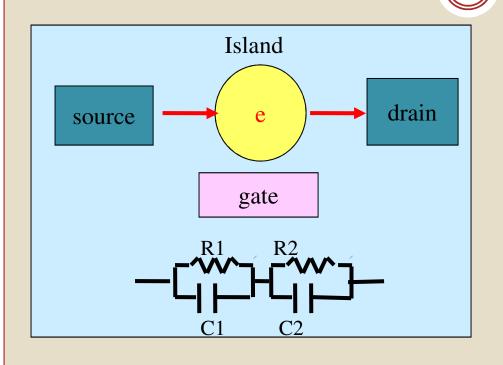
• 1987 Averin and Likharev Single Charge Transfer, Single Electron

Transistor at very low temperatures

• 1991 Fulton (Bell Labs) Single Charge Sensing Structure

- 1993 Nakazato and Ahmed, Dresselhaus and Likharev Single Electron Memory Prototype
- 1994 Many groups from Hitachi, IBM, Minesota, etc.
   Single Electron Memory at Room Temperature Using Quantum Dots
- 1996 Yano (Hitachi Central Lab)
  First Single Electron Memory Array, 64 bits.
- 1998 Yano (Hitachi Central Lab)
  First ULSI Single Electron Memory Prototype. 128 Mbits.
- 1999 Nakazato (Hitachi Cambridge) and Ahmed (Cavendish Lab)
  Announce Manufacturable Device for Next Generation Memory.

#### Coulomb Blockade Effect



#### Coulomb Blockade Effect

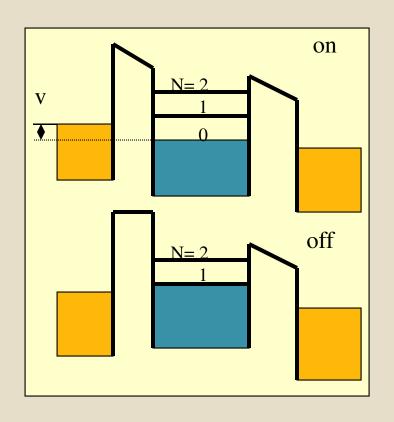
Quantum tunneling of electron between source and drain can be blocked If the charging energy

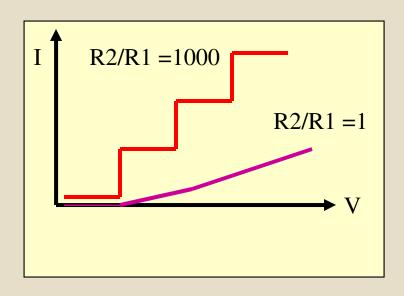
Ec = 
$$e^2/2C >> kT$$
  
 $\Delta E = eV - Ec < 0$ : blocked  
 $2Ec = e^2/(C_1 + C_2)$ 

#### Coulomb Staircase

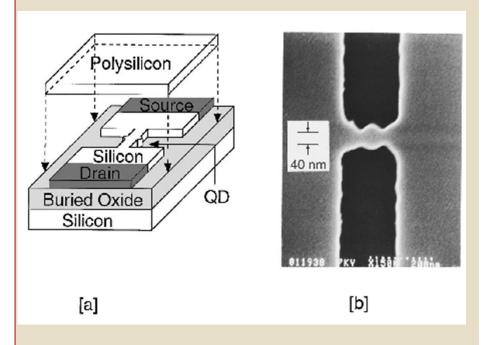
- Asymmetric junction (R2>>R1)
- Current steps at  $e/2C_2 + n(e/C_2)$

#### Coulomb Blockade Effect - Cont'd





#### SET at 100 K



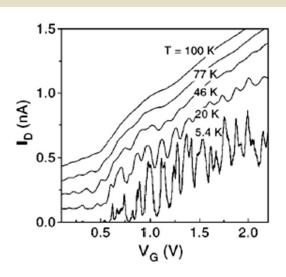
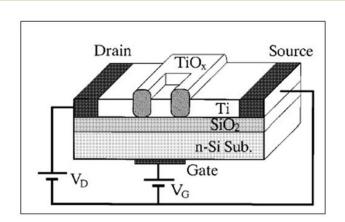


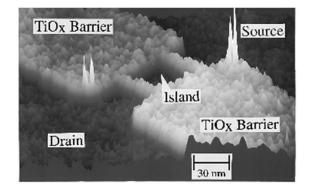
FIG. 2. The drain current  $I_D$  vs the gate voltage  $V_G$  of a Si QDT with 20 nm dot at different temperatures up to 100 K (curves are displaced for clarity). The  $V_{\rm DS}$  was kept at 50  $\mu$ V to prevent the drain bias from broadening the oscillations at 5.4 K significantly.

Si dot with 20nm diameter: energy spacing = 40meV Current oscillation due to the interference between different modes of quantum waves in a cavity

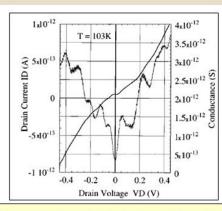
S.Y. Chou et al., Appl. Phys. Lett 67, 938 (1995)

# SET Operation at 300K

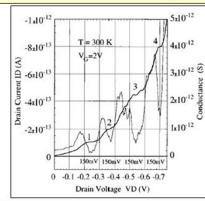




K. Matsumoto et al., Appl. Phys. Lett. 68, 34 (1996)

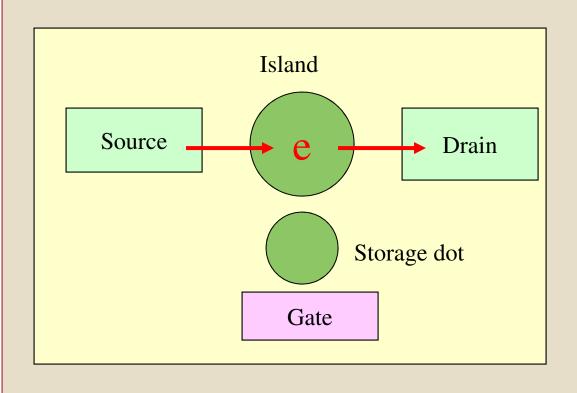


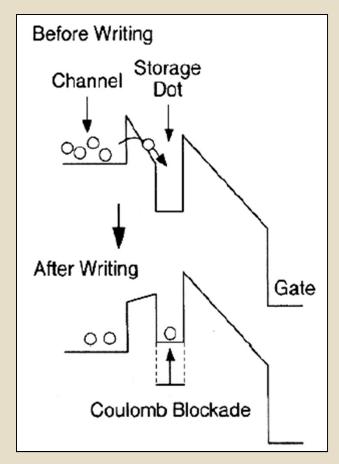
Unclear coulomb staircase due to the symmetric size of the tunnel juncton



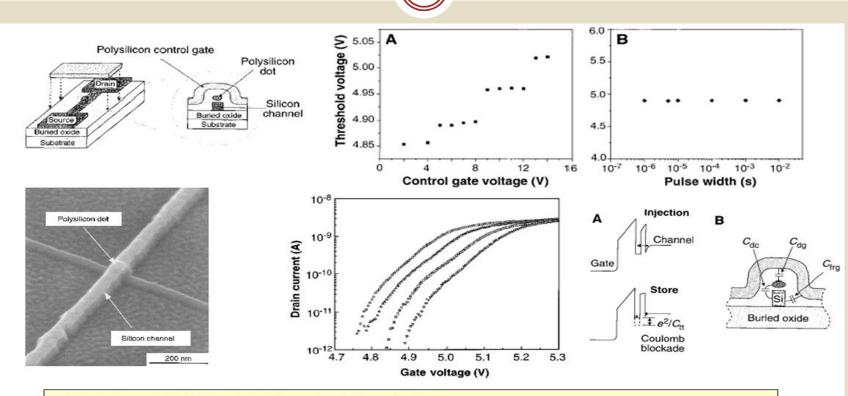
Coulomb staircase with periods of 150mV

## Single Electron Memory





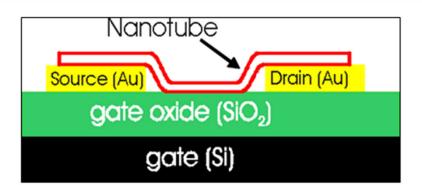
#### Single Electron Memory - Demonstration

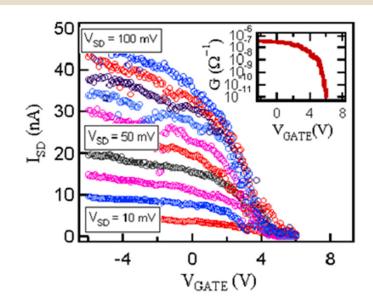


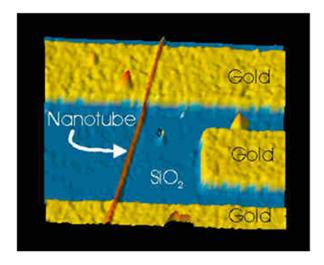
- Discrete shift in the threshold voltage
- •Staircase relation between the charging voltage and the shift
- Self-limiting charging process

L. Guo, E. Leobandung, S.Y. Chu, Science 275, 649 (1997)

#### Nanotube Single Electron Transistor



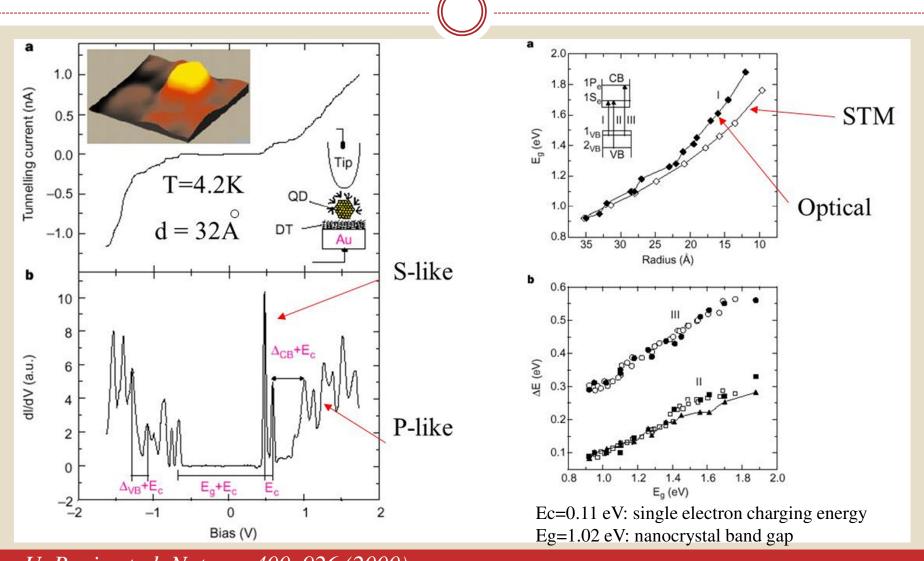




The amount of current ( $I_{SD}$ ) flowing through the nanotube channel can be varied by a factor of 100,000 by changing the voltage applied to a gate ( $V_{G}$ ),

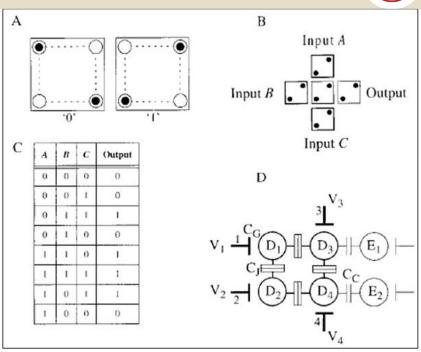
P. Avouris et al. , Appl. Phys. Lett, 73, 2447 (1998)

#### Tunneling Spectroscopy of InAs Quantum Dots



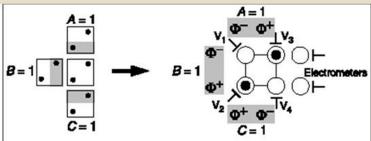
*U. Banin et al, Nature, 400, 926 (2000)* 

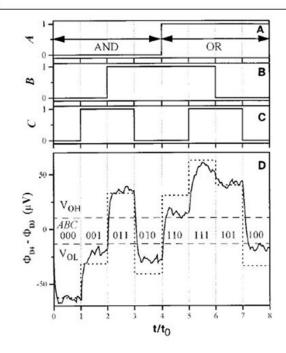
#### Quantum Dot Cellular Automata



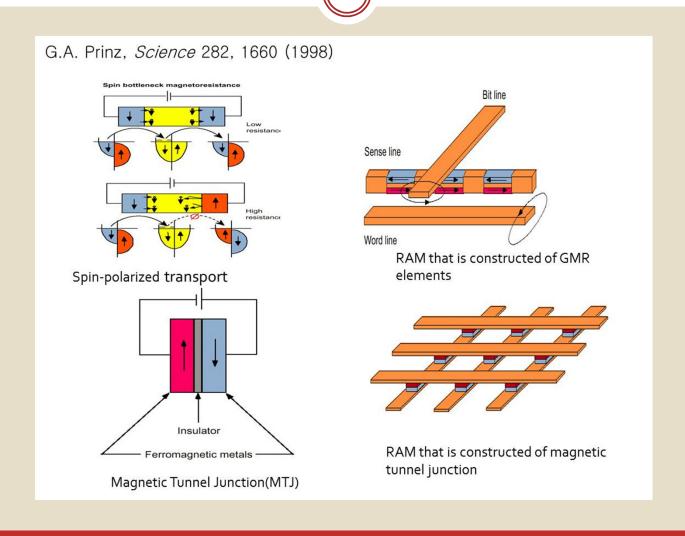
- Wireless interconnection
- •Communicate by the electric fields of electrons

I. Amlani et al., Science, 284, 289 (1999).





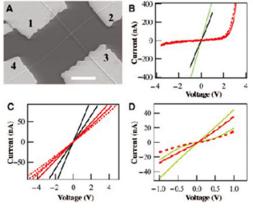
#### Magnetic Random Access Memory (MRAM)



#### **Nanowire Transistor**

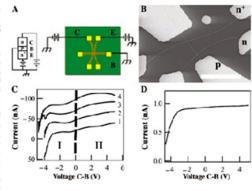


Fig. 1. Crossed SiNW junctions. (A) Typical FESEM image of a crossed SiNW junction with Al/Au contacts. The scale bar is 2 µm. The diameters of the NWs used in these studies ranged from 20 to 50 nm. (B through D) I-V behavior of p-n, p-p, and n-n junctions, respectively. The black and green curves correspond to the I-V behavior of individual p- and n-type SiNWs, respectively. The red curves represent I-V behavior of junctions. (B) The red curves correspond to fourterminal I-V through the p-n junction; the current values are multiplied by 10. The solid line corresponds to voltage drop measured between



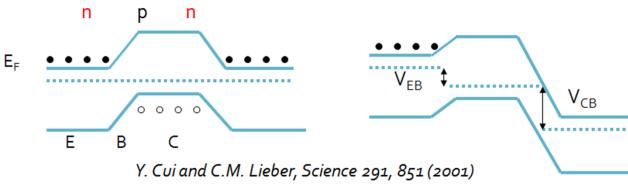
leads 3 and 4, and the dashed line to voltage between 3 and 2. (C and D) The red curves are two-terminal I-V through p-p and n-n junctions, respectively. The solid lines correspond to data from contacts 1-2, and the dashed lines correspond to data from the other three pairs (that is, 1 and 4, 2 and 3, and 3 and 4).

Fig. 2. Shown are n +-p-n SiNW bipolar transistors. (A) Schematics illustrating the common base configuration of an n +-p-n bipolar transistor (19) and the corresponding structure built from crossed SiNWs (right). The  $n^+$ -, p-, and n-type SiNWs function as emitter, base, and collector, respectively. (B) Typi-cal FESEM image of SiNW bipolar transistor. The three wires labeled as  $n^+$ . p, and n were used as emitter, base, and collector, respectively. Scale bar, 5 µm. (C) Collector current versus collector-base voltage recorded on an n+-p-n



transistor with emitter and collector SiNWs 15  $\mu$ m apart. Curves 1 to 4 correspond to the data recorded for emitter-base voltages of -1, -2, -3, -4 V, respectively. Regime I and II are separated by a dashed line, corresponding to saturation mode and active mode, respectively. (D), The common base current gain versus collector-base voltage.

- •Common base current gain: I<sub>C</sub>/I<sub>E</sub>=0.94
- •Common emitter current gain:  $I_C/I_B=16$



# Transistor Scaling: Beyond CMOS

Device	Operating Principle	Status	Advantages	Disadvantages
Resonant Tunneling Transistor	Quantum resonance in double barrier potential wells	Capable of large scale fabrication	Logic compression semiconductor based	Same scaling limitations as microelectronic transistor.
Single Electron Transistor	Coulomb Blockade in small quantum dots	Experimental only at very low temperatures	High gain. Similar in operation to FET	Low temperature. Difficult to control.
Quantum Dot Cell	Single electron confinement in arrays of Quantum dots	Quantum dots can be fabricated in the laboratory. Quantum dots are still theoretical.	Wireless. Low energy dissipation.	Difficult design rules. Susceptible to noise.
Molecular Shuttle Switch	Movement of a molecular "bead" between two stations on a switch molecule	Experimental, can only be switched chemically	Small, but robust. Assembly chemically.	Slow switching speed. How to interconnect?
Atom Relay	Vibrational movement of a single atom in and out of an atom wire	Theoretical	Very high speed. Sub- nanometer size.	Very low temperature. Very unreliable.
Refined Molecular Relay	Rotational movement of a group in and out of an atom wire	Theoretical	Sub- nanometer size. More reliable than atom relay.	How to fabricate? How to interconnect?